



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of)

Michael Steigerwald et al.)

Application No.: 10/825,240)

Filed: April 16, 2004)

For: ELECTRON MICROSCOPY SYSTEM,)
ELECTRON MICROSCOPY METHOD)
AND FOCUSING SYSTEM FOR)
CHARGED PARTICLES)

Group Art Unit: 2881

Examiner:

Confirmation No.: 7784

REQUEST FOR CORRECTED OFFICIAL FILING RECEIPT

Commissioner for Patents
Office of Initial Patent Examination
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P.O. Box 1450
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Sir:

Enclosed is a copy of the Official Filing Receipt marked in red to show correction that is needed. The correction is as follows:

In the Title section, please change "charges" to --charged--.

Also attached is a Supplemental Application Data Sheet reflecting the same change.


Issuance of a corrected Official Filing Receipt is respectfully requested.

Respectfully submitted,

BURNS, DOANE, SWECKER & MATHIS, L.L.P.

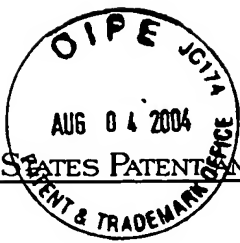
Date: August 4, 2004

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APPL NO.	FILING OR 371 (c) DATE	ART UNIT	FIL FEE REC'D	ATTY. DOCKET NO	DRAWINGS	TOT CLMS	IND CLMS
10/825,240	04/16/2004	2881	1682	007413-076	9	42	9

CONFIRMATION NO. 7784

21839
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FILING RECEIPT



OC000000013084671

Date Mailed: 06/28/2004

Receipt is acknowledged of this regular Patent Application. It will be considered in its order and you will be notified as to the results of the examination. Be sure to provide the U.S. APPLICATION NUMBER, FILING DATE, NAME OF APPLICANT, and TITLE OF INVENTION when inquiring about this application. Fees transmitted by check or draft are subject to collection. Please verify the accuracy of the data presented on this receipt. If an error is noted on this Filing Receipt, please write to the Office of Initial Patent Examination's Filing Receipt Corrections, facsimile number 703-746-9195. Please provide a copy of this Filing Receipt with the changes noted thereon. If you received a "Notice to File Missing Parts" for this application, please submit any corrections to this Filing Receipt with your reply to the Notice. When the USPTO processes the reply to the Notice, the USPTO will generate another Filing Receipt incorporating the requested corrections (if appropriate).

Applicant(s)

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Assignment For Published Patent Application

LEO Elektonenmikroskopie GmbH, Oberkochen, GERMANY;

Domestic Priority data as claimed by applicant

Foreign Applications

GERMANY 10317894.5 04/17/2003

If Required, Foreign Filing License Granted: 06/26/2004

Projected Publication Date: To Be Determined - pending completion of Missing Parts

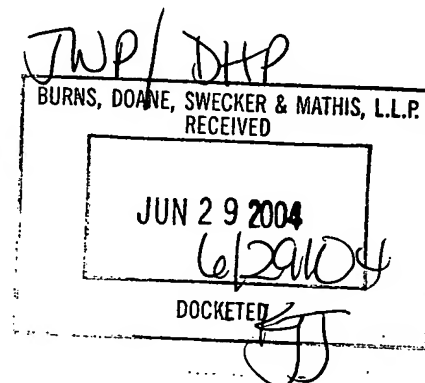
Non-Publication Request: No

Early Publication Request: No

Title

Electron microscopy system, electron microscopy method and focusing system for charged particles

charged



all
7/6/04